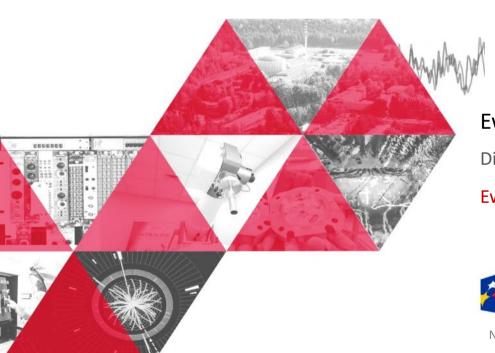
Crystal lattice defects induced by swift heavy ions in 3C-SiC: study of repair mechanisms at high temperatures





Ewelina Kucal

Division of Nuclear Energy and Environmental Studies

Ewelina.Kucal@ncbj.gov.pl



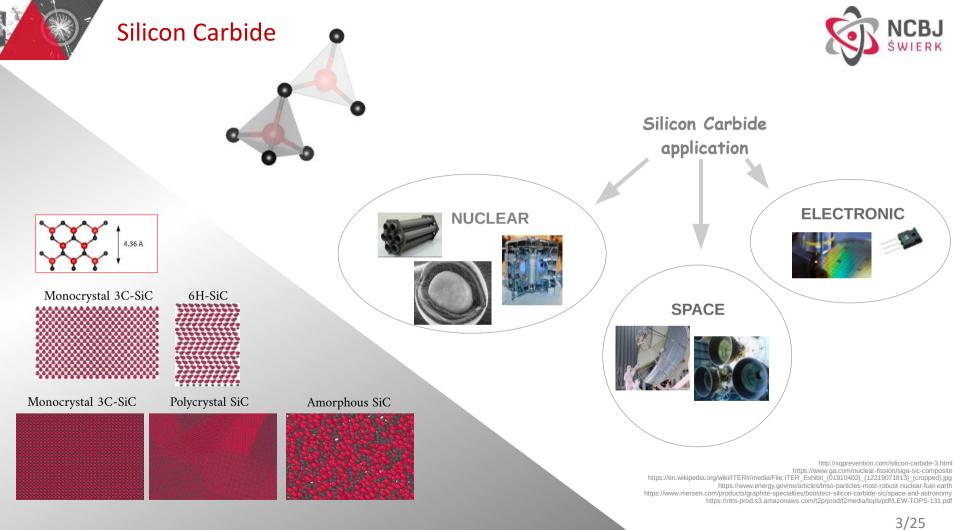








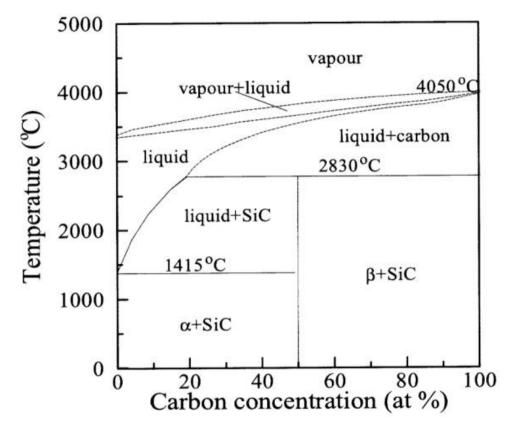
- Silicon Carbide
- Ion irradiation damage
- Si and C ion irradiation of SiC experimental results
- MD simulations of low energy ion irradiation
- Thermal Spike model
- MD simulation of TS model
- Conclusion





Silicon Carbide







Ion radiation damage



Energetic incident ions lose their energy through two different energy processes:

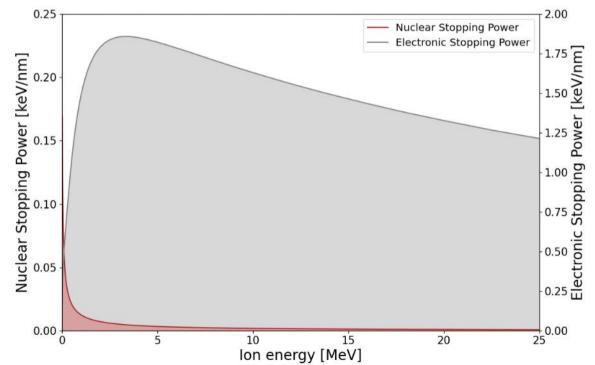
→ Nuclear energy loss

the transfer of kinetic energy occurs via elastic scattering

→ Electronic energy loss

the inelastic transfer of energy to electrons (i.e. ionization and excitation)

Stopping Power for C ions in SiC





Displacement per atom



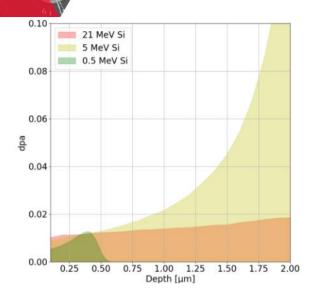
- Atomic displacements per atom (dpa) is unit of radiation damage exposure
- The current international standard definition for dpa is based on the Norgett-Robinson Torrens (NRT) model that convert a known value of the damage energy into a corresponding number of atomic displacements
- The Norgett-Robinson-Torrens model:

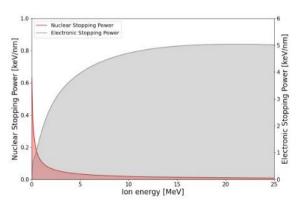
$$v_{NRT} = \frac{0.8T_d}{2E_d}$$

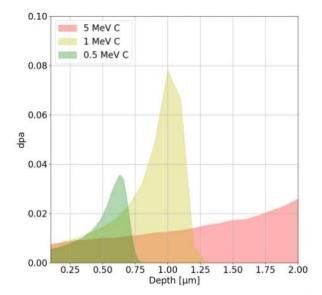
 T_d - damage energy,

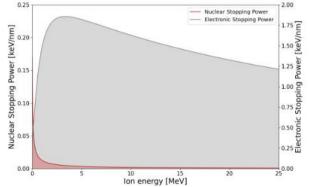
 E_d - displacement energy,

Si and Cions irradiation of SiC

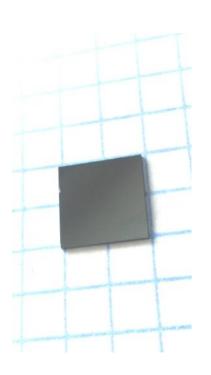








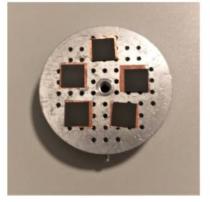


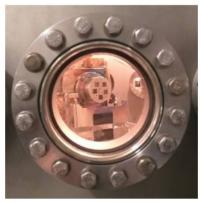


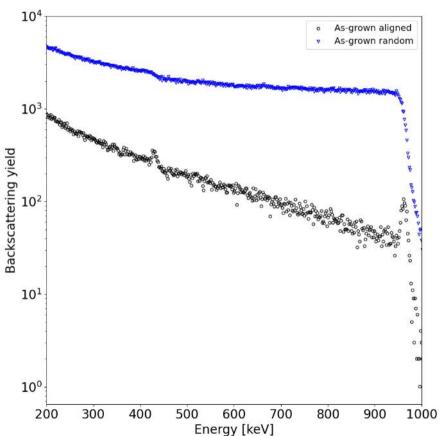


Rutherford Backscattering Spectrometry analysis





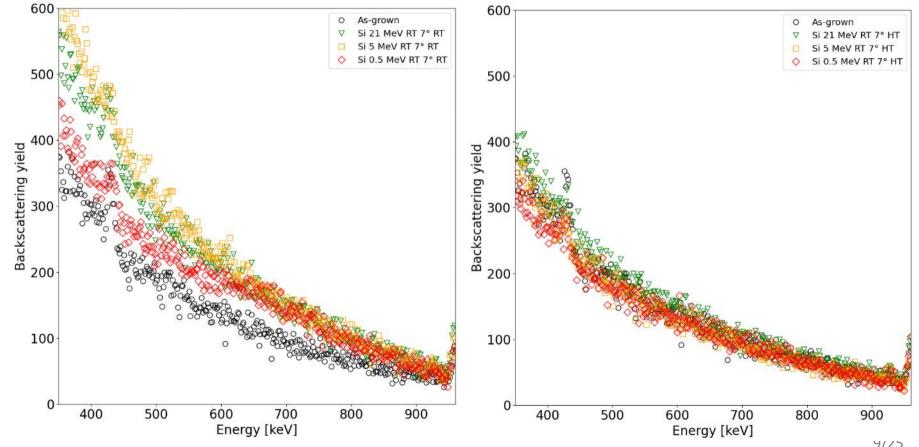






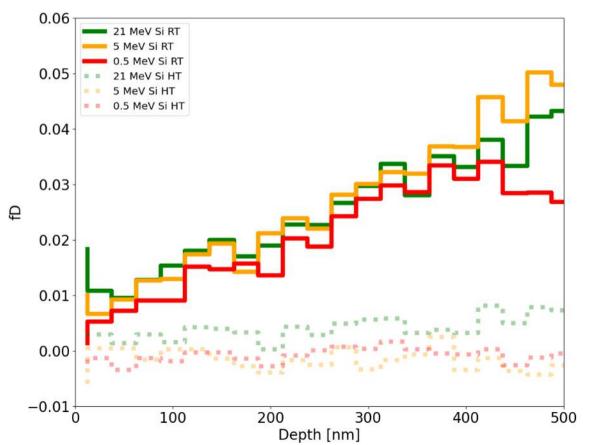
Rutherford Backscattering Spectrometry analysis











Relative defect farction:

$$f_D = \frac{Y_{aligned}^{irradiated} - Y_{aligned}^{as-grown}}{Y_{random}}$$

 $Y_{aligned}^{irradiated}$

Yield of the irradiated sample

 $Y_{aligned}^{as-grown}$

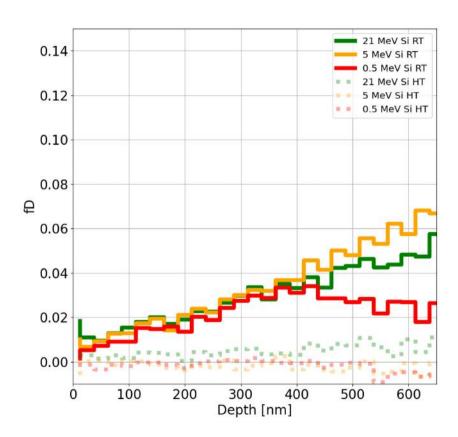
Yield of the as-grown sample

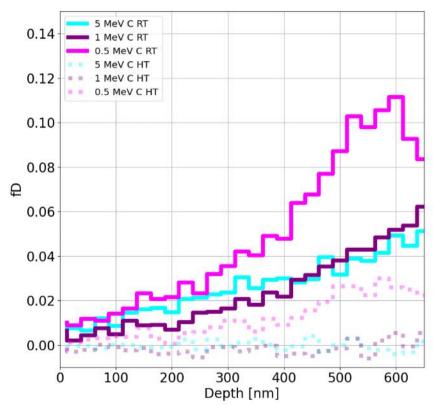
 Y_{random}

Random Yield



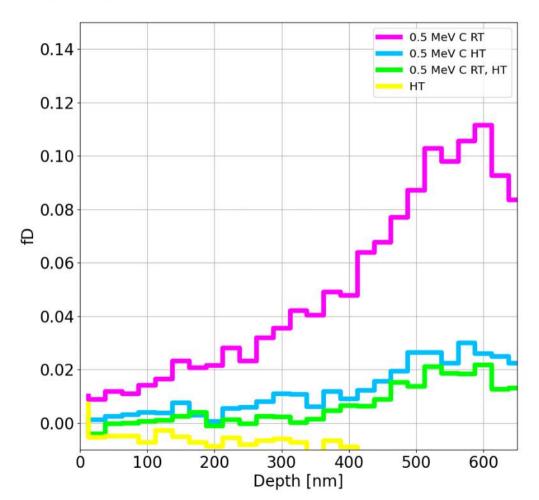






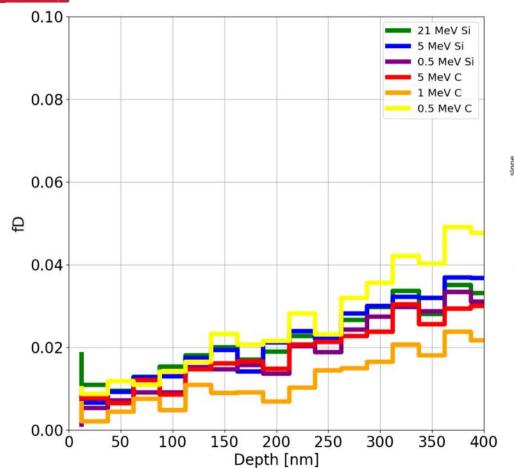


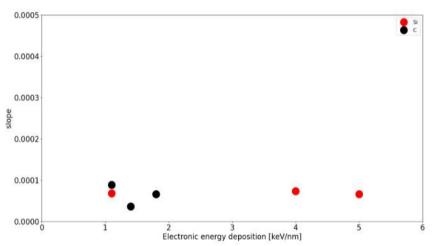










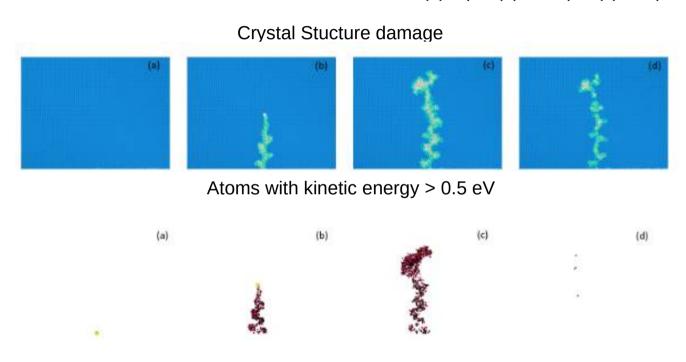




Molecular dynamic simulations



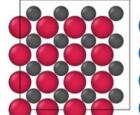
Simulation of 5keV Ar ion irradiation of SiC at time: (a) 0 ps, (b) 0.06 ps, (c) 0.2 ps, (d) 3.2 ps

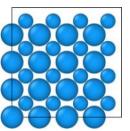


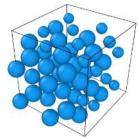


Ovito analysis

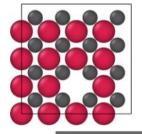


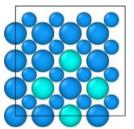


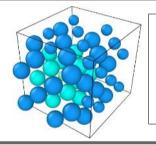




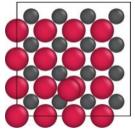
1	Cluster analysis (cutoff: 2): 0 cluster	Color	Structure	Count	Fraction	ld
			Other	0	0.0%	0
	WS analysis: 0 vacancies 0 interstitials		Cubic diamond	64	100.0%	1
			Cubic diamond (1st neighbor)	0	0.0%	2
			Cubic diamond (2nd neighbor)	0	0.0%	3

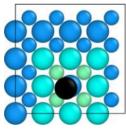


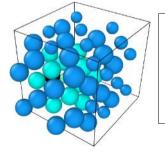




	Color	Structure	Count	Fraction	Id
Cluster analysis (cutoff: 2): 1 cluster		Other	0	0.0%	0
		Cubic diamond	47	74.6%	1
WS analysis: 1 vacancies		Cubic diamond (1st neighbor)	12	19.0%	2
0 interstitials		Cubic diamond (2nd neighbor)	4	6.3%	3







Shiptor analysis (******* a):	Color	Structure	Count	Fraction	Id
Cluster analysis (cutoff: 2): 1 cluster		Other	1	1.6%	0
WS analysis:		Cubic diamond	47	73.4%	1
1 vacancies		Cubic diamond (1st neighbor)	12	18.8%	2
1 interstitials		Cubic diamond (2nd neighbor)	4	6.3%	3



Electronic Stopping Power in MD simulations



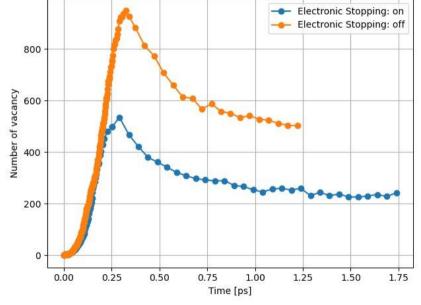
- Fix electron/stopping implements inelastic energy loss for fast ions in solids
- It applies a friction force to fast moving atoms to slow them down due to

electronic stopping

$$m_i \frac{\partial \mathbf{v_i}}{\partial t} = \mathbf{F_i}(t)$$



$$m_i \frac{\partial \mathbf{v_i}}{\partial t} = \mathbf{F_i}(t) \left(-\frac{\mathbf{v_i}}{|\mathbf{v_i}|} S \right)$$

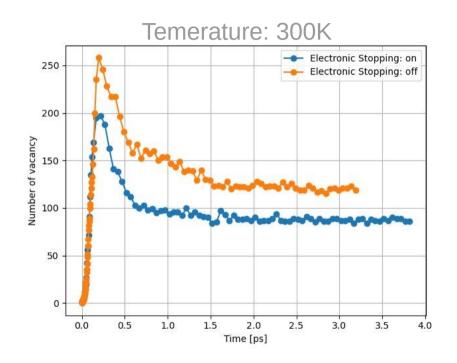


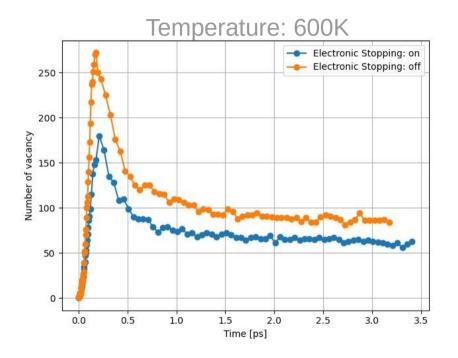
Ar ion irradiation of SiC (20 keV)



Number of vacancies produced during the 5 keV Ar cascades





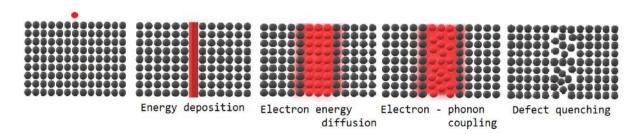






The heat diffusion in the electron and lattice subsystems can be described by two coupled differential equations governing the energy diffusion on the electron and atomic subsystems and their exchange via the electron-phonon coupling

$$C_e(T_e)\frac{\partial T_e}{\partial t} = \frac{1}{r}\frac{\partial}{\partial r}\left[rK_e(T_e)\frac{\partial T_e}{\partial r}\right] - g(T_e - T_a) + A(r,t)$$
$$C_a(T_a)\frac{\partial T_a}{\partial t} = \frac{1}{r}\frac{\partial}{\partial r}\left[rK_a(T_a)\frac{\partial T_a}{\partial r}\right] + g(T_e - T_a)$$

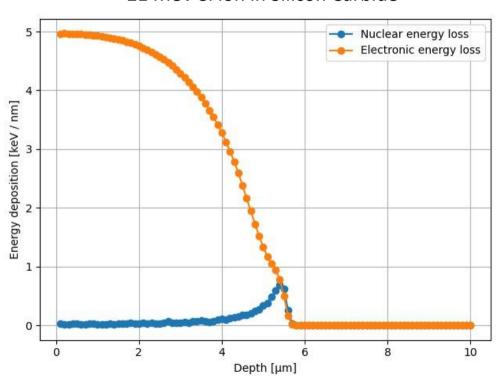


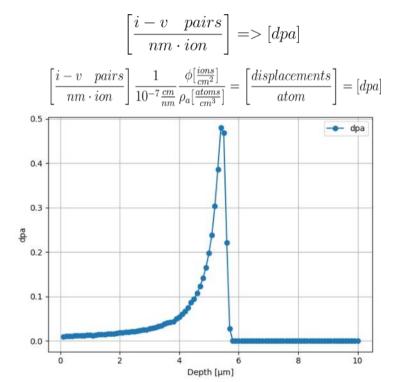


Energy deposition & dpa calculation with using TRIM



21 MeV Si ion in Silicon Carbide



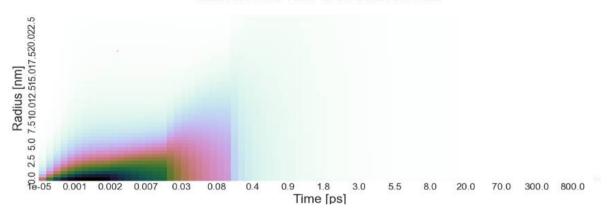




21 MeV Si ion irradiation of SiC



ELECTRONIC TEMPERATURE PROFILE

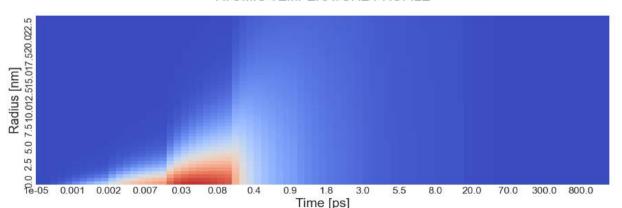


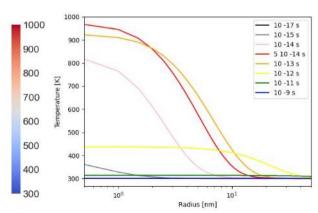
Results from Thermal Spike 2.15 Gui code (TS code developed by C. Dufour, J. Rangama, M. Toulemonde)

10⁴

10³

ATOMIC TEMPERATURE PROFILE





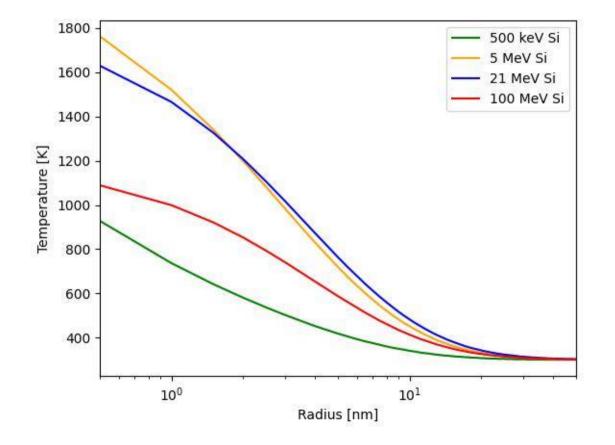
20/25



Thermal Spike



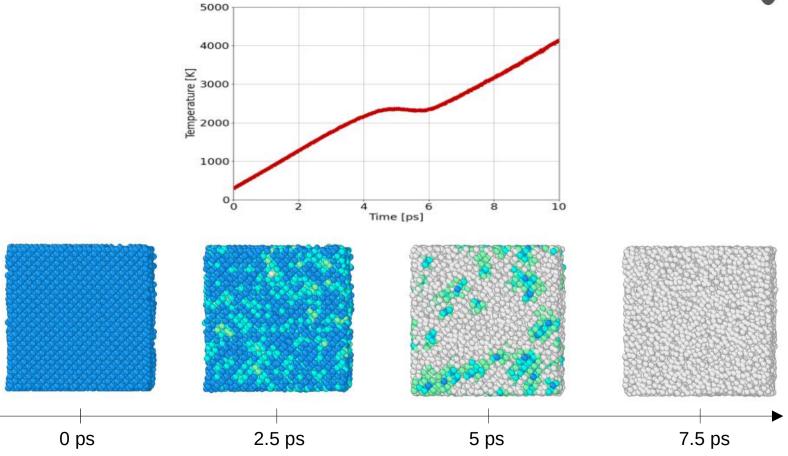
Results from Thermal Spike 2.15 Gui code (TS code developed by C. Dufour, J. Rangama, M. Toulemonde)





SiC melting

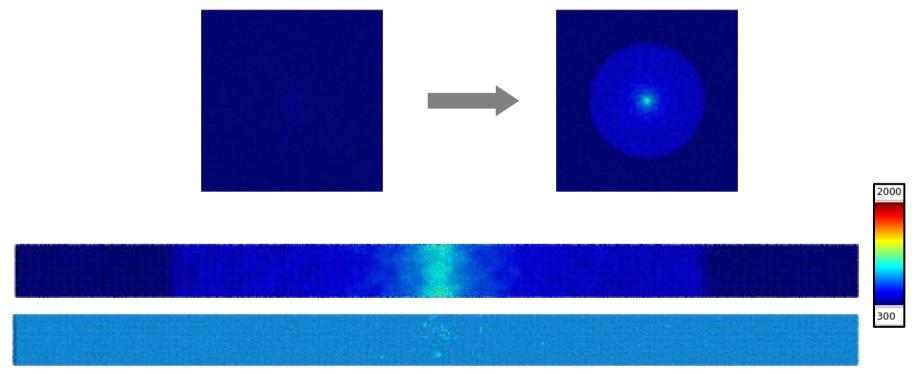






Thermal Spike, MD simulations







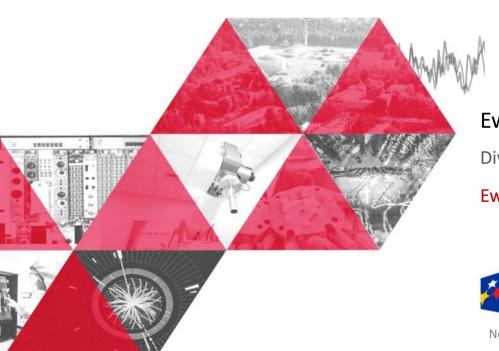


- ➤ The temperature effects on damage production during ion irradiation were presented. It can be seen that defects are almost non-existent in Si and C ion irradiation at high temperatures.
- ➤ This presentation shows a study of the role of coupled nuclear and electron energy deposition effects in SiC during ion irradiation.
- Calculation based on Thermal Spike model suggested that electronic energy deposition can affect on crystal structure evolution, even if increased temperature is below melting point.

The research leading to this result has been supported by the RADIATE project and the NCBR project "New Reactor Concepts and Safety Analyses for the Polish Nuclear Energy Program", POWR.03.02.00-00-1005/17 (years 2018-2023).

Thank you for attention





Ewelina Kucal

Division of Nuclear Energy and Environmental Studies

Ewelina.Kucal@ncbj.gov.pl





